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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/658,291	09/10/2003	Naoyuki Tamura	648.41957CX1	2459
20457	7 7590 10/19/2005		EXAMINER	
ANTONELLI, TERRY, STOUT & KRAUS, LLP 1300 NORTH SEVENTEENTH STREET			MOORE, KARLA A	
SUITE 1800	1 SEVENTEENTH STRE	SE 1	ART UNIT	PAPER NUMBER
ARLINGTO	ARLINGTON, VA 22209-3873			
	•		DATE MAILED: 10/19/2005	

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)
Office Action Summary		10/658,291	TAMURA, NAOYUKI
		Examiner	Art Unit
	•	Karla Moore	1763
Period fo	The MAILING DATE of this communication apport	pears on the cover sheet with the c	orrespondence address
WHI(- Exte after - If NO - Failt Any	ORTENED STATUTORY PERIOD FOR REPLICATION OF THE MAILING DON'S INC. SIX (6) MONTHS from the mailing date of this communication. Operiod for reply is specified above, the maximum statutory period rize to reply within the set or extended period for reply will, by statute reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tin will apply and will expire SIX (6) MONTHS from 6, cause the application to become ABANDONE	N. nely filed the mailing date of this communication. D (35 U.S.C. § 133).
Status			
1)⊠ 2a)□ 3)□	Responsive to communication(s) filed on <u>20 Jac</u> This action is FINAL . 2b) This Since this application is in condition for alloward closed in accordance with the practice under E	s action is non-final. nce except for formal matters, pro	
Disposit	ion of Claims		
5)□ 6)⊠ 7)□ 8)□ Applicat 9)□	Claim(s) <u>5-8</u> is/are pending in the application. 4a) Of the above claim(s) is/are withdraw Claim(s) is/are allowed. Claim(s) <u>5-8</u> is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/or ion Papers The specification is objected to by the Examine The drawing(s) filed on <u>10 September 2003</u> is/s Applicant may not request that any objection to the	or election requirement. er. are: a)⊠ accepted or b)⊡ objec	
11)[]	Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Ex		
	under 35 U.S.C. § 119	Commerciation of the attached office	ACION OF IOIN F 10-152.
12)⊠ a)l	Acknowledgment is made of a claim for foreign All b) Some * c) None of: 1. Certified copies of the priority document: 2. Certified copies of the priority document: 3. Copies of the certified copies of the priority document application from the International Bureau See the attached detailed Office action for a list	s have been received. s have been received in Applicationity documents have been received (PCT Rule 17.2(a)).	on No. <u>10/218,406</u> . ed in this National Stage .
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2) 🔲 Notic 3) 🔲 Inforr	t(s) e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) r No(s)/Mail Date	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:	(PTO-413) ate atent Application (PTO-152)

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DETAILED ACTION

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 5-8 are rejected under 35 U.S.C. 102(b) as being anticipated by U.S. Patent No. 6,198,976 to Sundar et al.
- 3. Sundar et al. disclose a vacuum processing method for transferring a wafer in atmospheric air to a predetermined position within a vacuum processing chamber (Figure 2B, 114) using a atmospheric equipment (128) disposed in an atmospheric transfer unit (120) and performing a predetermined treatment to said wafer in said vacuum processing chamber; said method comprising: an atmospheric transfer step (column 12, rows 50-54 and rows 58-60) of transferring said wafer in atmospheric air to a said vacuum transfer chamber (112) using an atmospheric transfer equipment disposed in atmospheric air; a vacuum transfer step (column 12, rows 60-63) of transferring a wafer received from said atmospheric transfer equipment to a position for said predetermined treatment within said vacuum processing chamber using vacuum transfer equipment (116) disposed within said vacuum transfer chamber connecting said atmospheric transfer unit and said vacuum processing chamber; a step of detecting the displacement of said wafer (column 12, rows 63-65) in a transverse direction (the displacement can be detected while moving any direction) with respect to a traveling direction near an ingress path of said wafer to said vacuum processing chamber by comparing a correct position said wafer passing a line which is predetermined in advance with an actual position of said wafer being transferred by said vacuum transfer equipment; and a step of moving a vacuum robot of said vacuum transfer equipment (column 6, rows 27-38) which transfers said wafer in the transverse direction with respect to the traveling direction as to correct the detected displacement of the wafer (or a step of correcting the displacement of said wafer by moving an arm of said vacuum transfer equipment in the transverse

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direction with respect to the traveling direction based on the result of detection performed by a wafer

position sensor, which is commensurate with the prior step).

4. With respect to claim 7/5 and 7/6, said step of detecting the displacement of said wafer comprises

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a step of detecting the rim position of said wafer being transferred in the vacuum transfer step (column 5.

rows 1-3).

5. With respect to claim 8/5 and 8/6, initial positioning of said wafer is performed in atmosphere (),

and the displacement of said wafer is detected directly before the processing within said vacuum

processing chamber (column 11, rows 1-18).

Response to Arguments

6. Applicant's arguments with respect to claims 5-8 have been considered but are most in view of

the new ground(s) of rejection. New art has been relied upon to account for the amended claims.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should

be directed to Karla Moore whose telephone number is 571.272.1440. The examiner can normally be

reached on Monday-Friday, 8:30am-5:30pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor,

Parviz Hassanzadeh can be reached on 571.272.1435. The fax phone number for the organization

where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application

Information Retrieval (PAIR) system. Status information for published applications may be obtained from

either Private PAIR or Public PAIR. Status information for unpublished applications is available through

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at 866-217-9197 (toll-free).

Patent Examiner

17 October 2005